

FIG. 1A

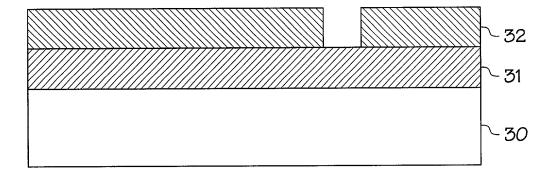


FIG. 1B

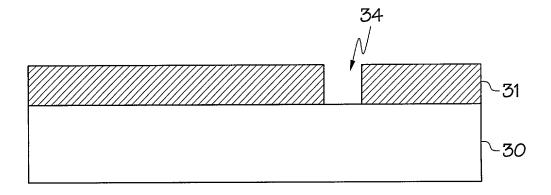


FIG. 1C

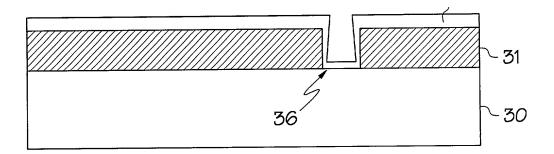


FIG. 1D

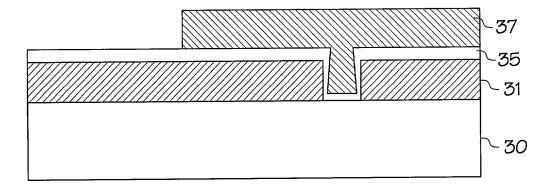


FIG. 1E

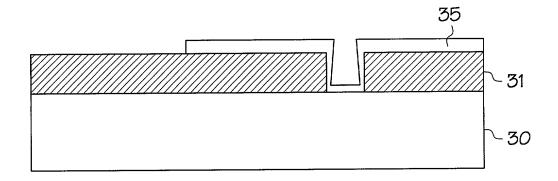


FIG. 1F

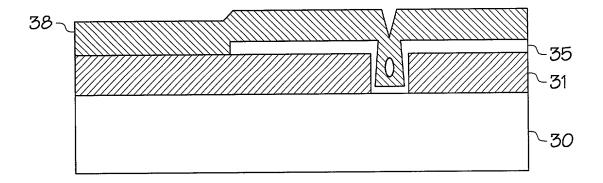


FIG. 1G

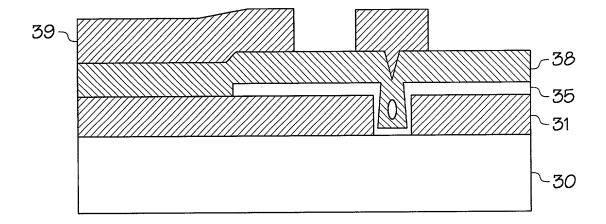


FIG. 1H

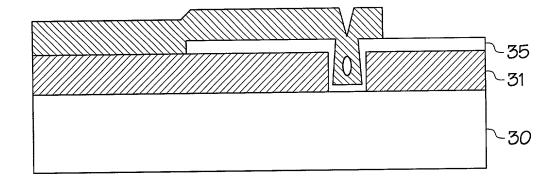


FIG. 11

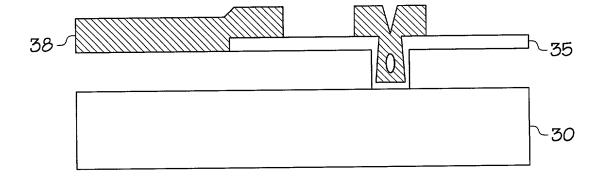


FIG. 1J

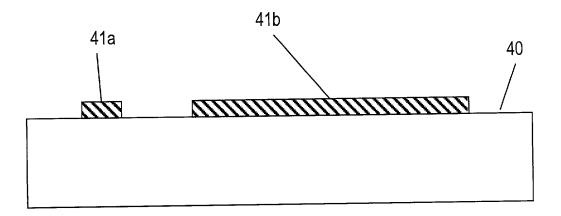


FIG. 2A

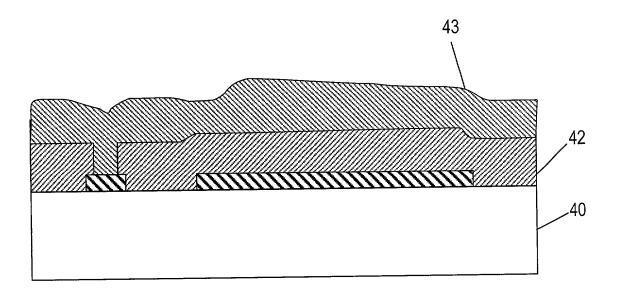


FIG. 2B

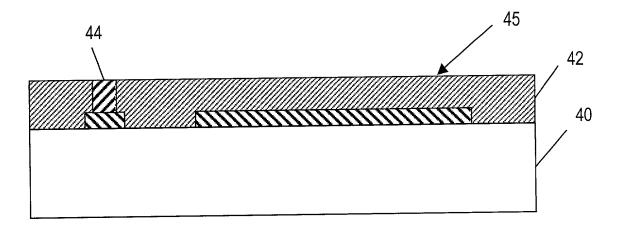


FIG. 2C

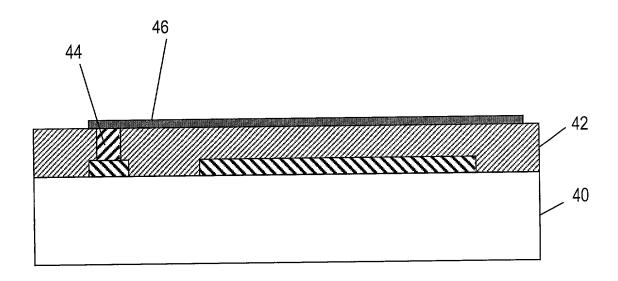


FIG. 2D

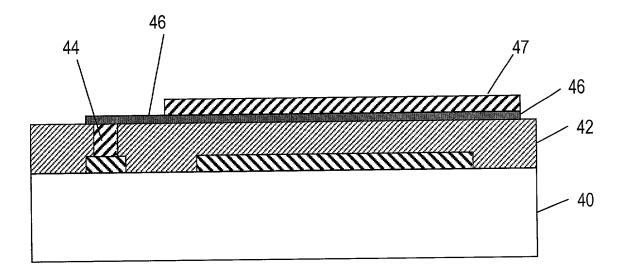


FIG. 2E

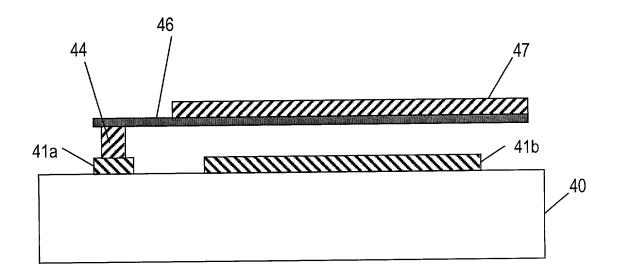


FIG. 2F

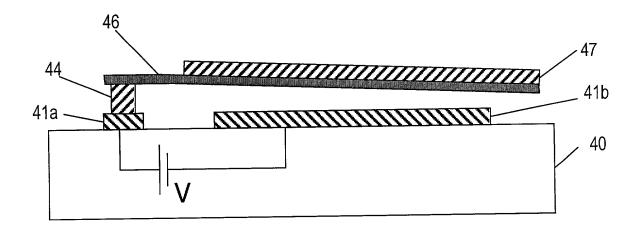
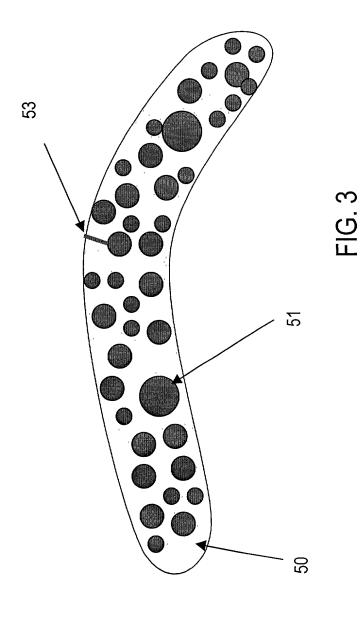
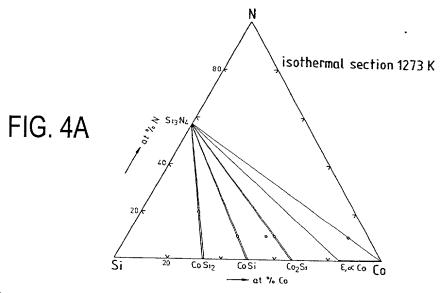
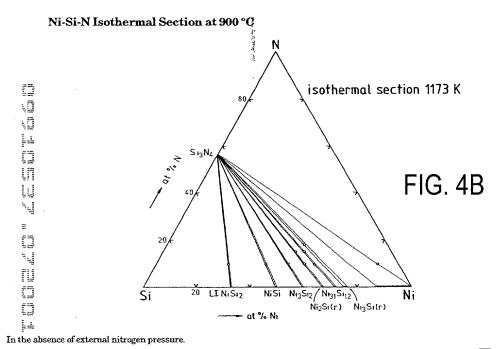


FIG. 2G

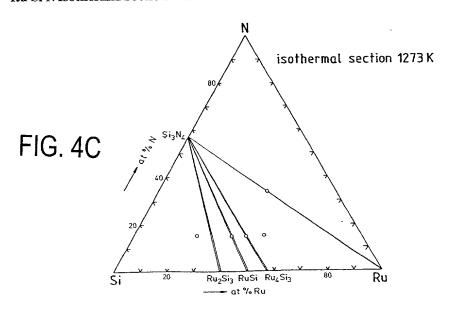


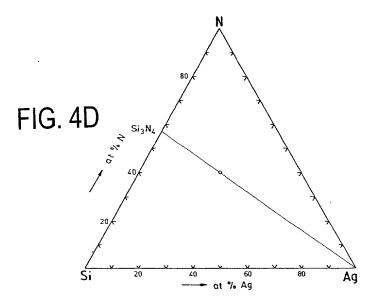


In the absence of external nitrogen pressure.

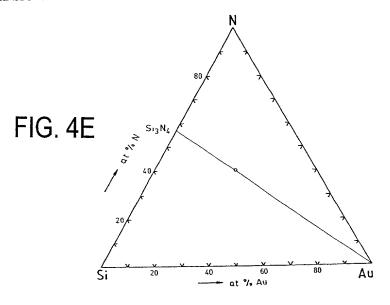


Ru-Si-N Isothermal Section at 1000 $^{\circ}\text{C}$

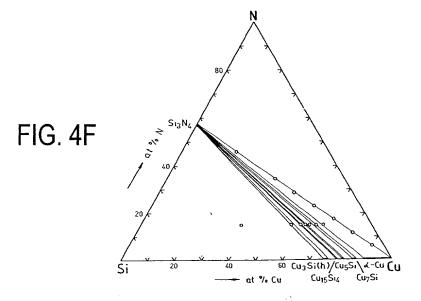


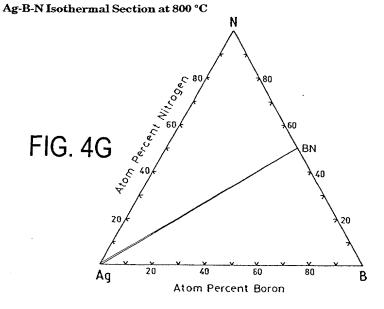


Au-Si-N Isothermal Section at 900 °C

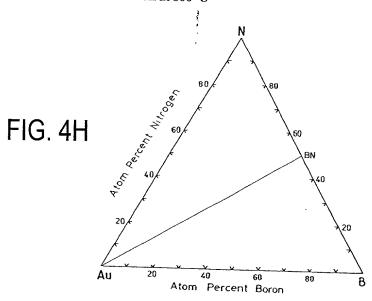


Cu-Si-N Isothermal Section at 700 $^{\circ}\mathrm{C}$

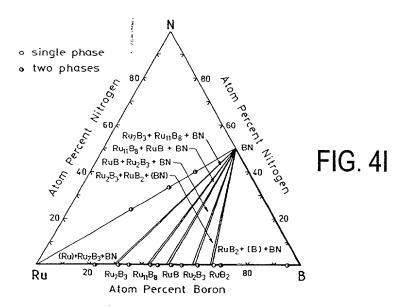




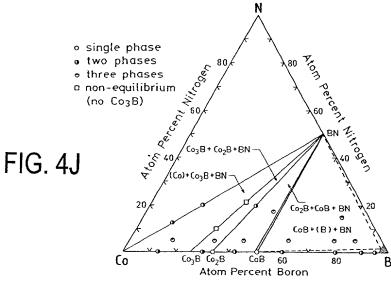
Au-B-N Isothermal Section at 800 $^{\circ}\mathrm{C}$



Ru-B-N Isothermal Section at 1200 °C Under 10⁵ Pa of Argon

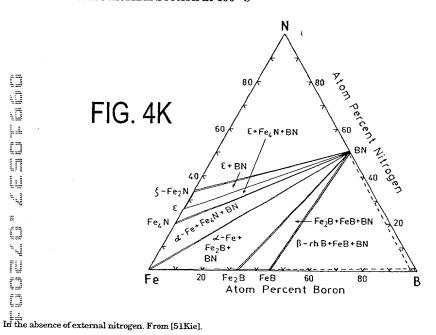


Co-B-N Isothermal Section at 900 °C Under 10⁵ Pa of Argon

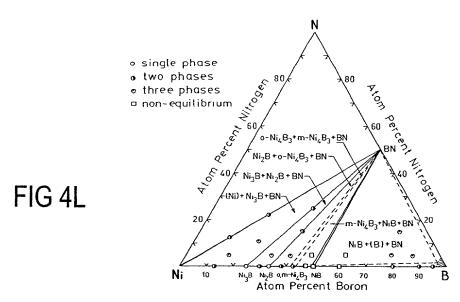


Fe-B-N Isothermal Section at 400 °C

In the absence of external nitrogen.



Ni-B-N Isothermal Section at 900 °C Under 10^5 Pa of Argon



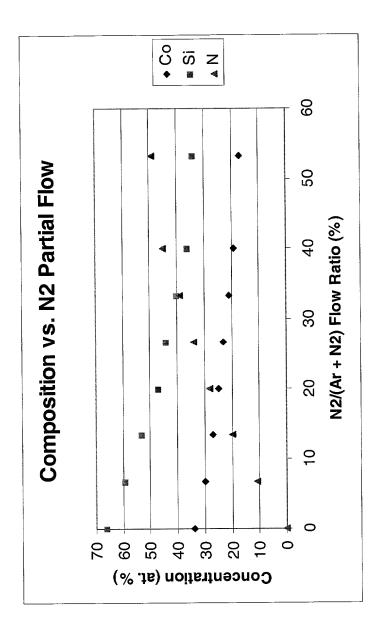


FIG. 5

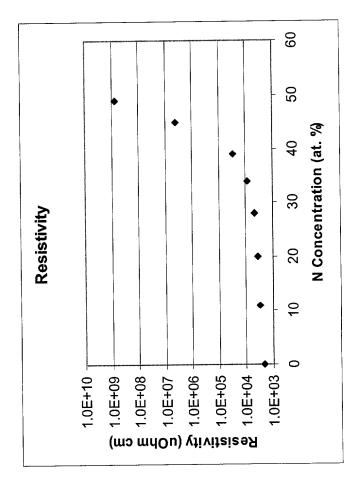


FIG. 6

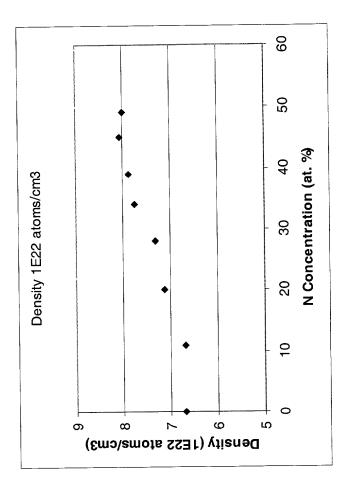


FIG. 7

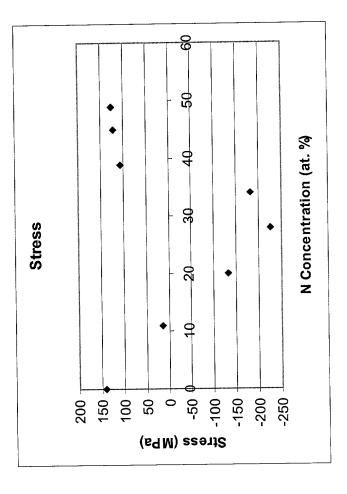


FIG. 8

30 sccm 270 202	Etching rate comparasion Letting rate comparasion Letting base 20 sccm N2 in CosiN	
20 sccm 230 202	Etching rate	
10 sccm 200 133	280 260 240 220 200 180 160 140 120 100 100 100	
CI2 base CF4 base	Etch rate (A/min)	

FIG. 9